

Supporting Information

A broad range and piezoresistive flexible pressure sensor based on carbon nanotube network dip-coated porous elastomer sponge

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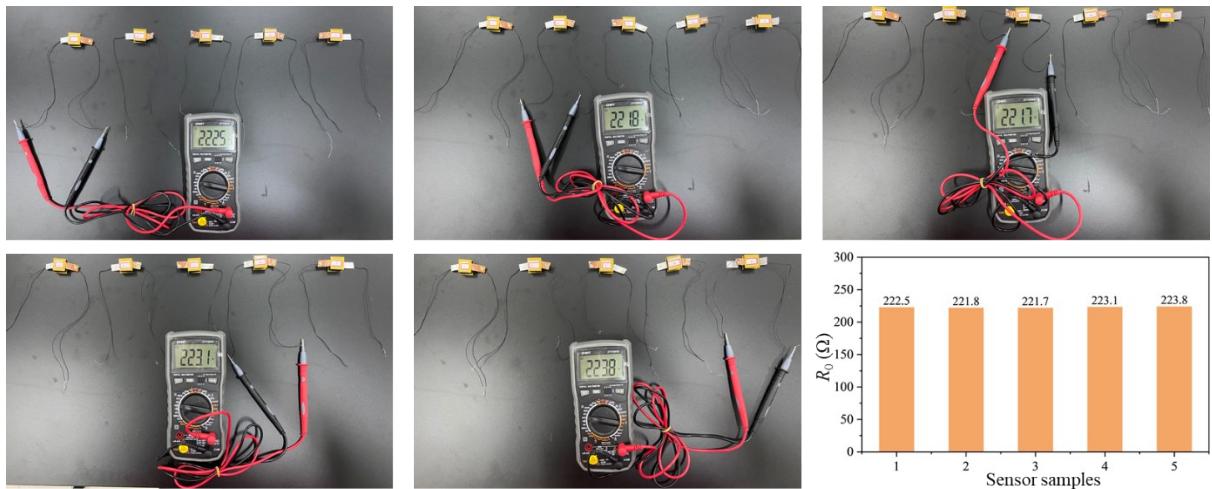


Fig. S1. The initial resistances (R_0) of the as-prepared 5 sensor samples.

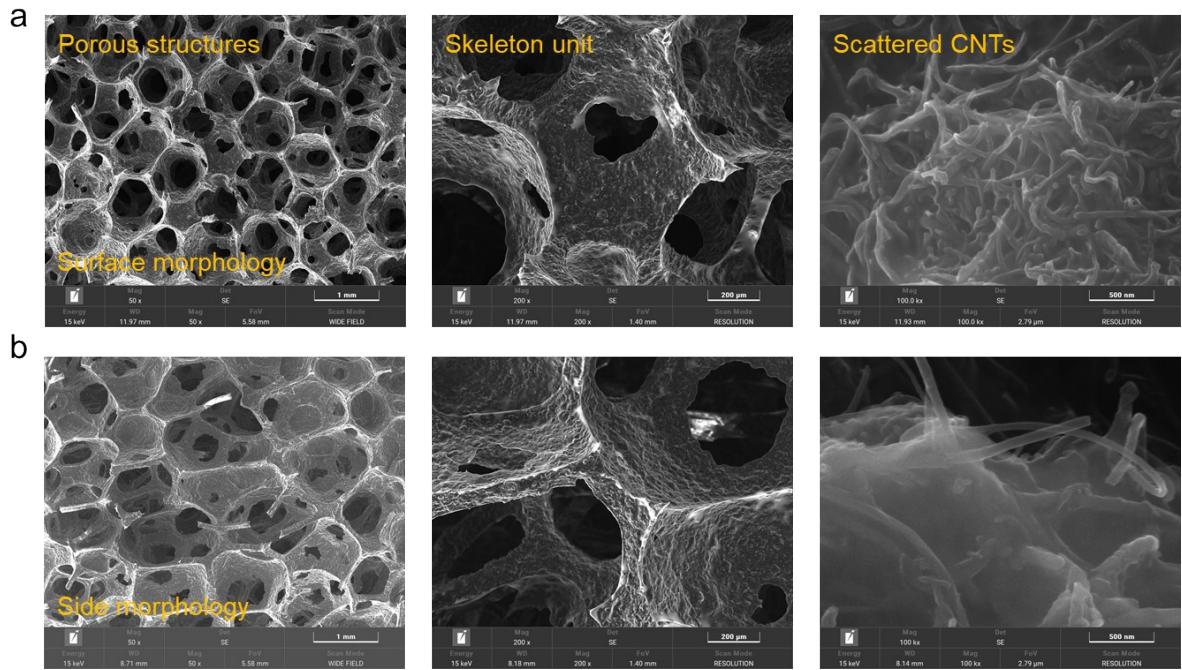


Fig. S2. a) SEM images of the surface morphology of the pressure sensor. b) SEM images of the side morphology of the pressure sensor.

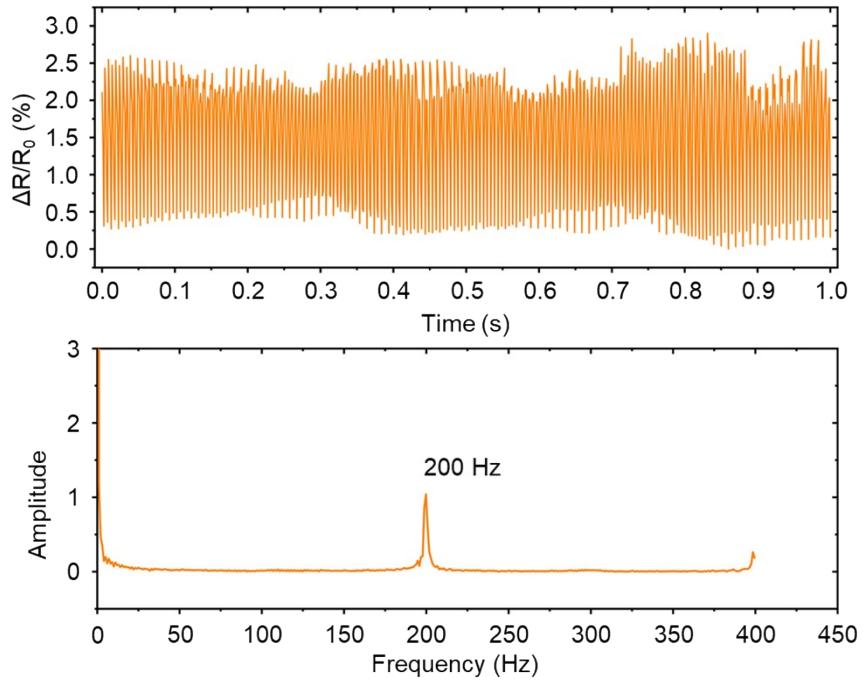


Fig. S3. The response of the sensor under an applied pressure with a frequency load of 200 Hz, and FFT result according to the response signals.

Supplementary Tables

Table S1 Comparison of the properties of the sponge-based pressure sensor in the references and that in our work

| Materials | Methods | Sensor types | Sensitivity [kPa ⁻¹] | Detection limit [Pa] | Working range [kPa] | Response and recovery time [ms] | Stability | Ref |
|-----------------------------------|--------------------------------|------------------|----------------------------------|----------------------|---------------------|---------------------------------|-------------|------------------|
| PET-ITO/PDMS | Physical foaming | Capacitive | 0.796 | 4 | 25 | 65 | 1000 | [1] |
| Melamine foam/MWCNTs/MXene | Soaking | Resistant | 0.339 | / | 180 | 180/140 | 1150 | [2] |
| Al/PVC/PDMS | Gas evaporation | Capacitive | 0.375 | / | 230 | 190 | 50 | [3] |
| Graphene/PDMS | Sugar dissolving & Dip-coating | Capacitive | 0.137 | 50 | 12 | / | 100 | [4] |
| Carbon ink/melamine | Dip-coating | Resistant | 0.056 | 30 | 31.36 | 100/100 | 2000 | [5] |
| Carbon ink/Melamine foam | Dip-coating | Resistant | 0.62 | / | 150 | 30/55 | 2500 | [6] |
| MWCNTs/PDMS | Gas evaporation | Capacitive | 0.19 | / | 300 | 180 | 35 | [7] |
| AgNW/CF/PDMS | Sugar dissolving | Capacitive | 0.161 | / | 200 | / | 6000 | [8] |
| MXene/rGO/PDMS | Freeze-drying | Resistant | 3.75 | 1.5 | 28 | 20/40 | 2000 | [9] |
| AgNP/PDMS | NaCl dissolving | Resistant | 0.41 | 25 | 120 | 30 | 1500 | [10] |
| Graphene/styrene-butadiene rubber | Dip-coating | Resistant | 1.05 | / | 150 | / | 3000 | [11] |
| MXene/PANI | Hydrazine-induced foaming | Resistant | 690.91 | / | 19.12 | 106/95 | 10000 | [12] |
| MWCNT/PU | Dip coating | Resistant | 0.00125 | 150 | 350 | 401/473 | 5000 | This work |

References:

- 1 Z. Song, L. Zhao, C. Chang, Y. Zhou, W. An and S. Yu, *J. Electron. Mater.*, 2022, **51**, 7173–7181.
- 2 Y. Su, K. Ma, X. Mao, M. Liu and X. Zhang, *Nanomaterials*, 2022, **12**, 2225.
- 3 S. Dervin, E. S. Hosseini and R. Dahiya, *IEEE Sens. J.*, 2021, **22**, 9914–9921.
- 4 L. A. Kurup, C. M. Cole, J. N. Arthur and S. D. Yambem, *ACS Appl. Nano Mater.*, 2022, **5**, 2973–2983.
- 5 X. Zhang, J. Li, J. Lin, W. Li, W. Chu and X. Wang, *J. Mater. Sci. Mater. Electron.*, 2022, **33**, 13731–13742.
- 6 C. Liu, Q. Tan, L. Kong, Y. Deng, X. Ma, L. Xu, Y. Xu, W. Zhou, L. Zhong, Q. Qiang, T. Han, W. Chen and B. Liu, *Mater. Lett.*, 2023, **330**, 133331.
- 7 Z. Yun, K. Li, H. Jiang and X. Tang, *Sensors*, 2022, **22**, 2607.
- 8 S. W. Park, P. S. Das, A. Chhetry and J. Y. Park, *IEEE Sens. J.*, 2017, **17**, 6558–6564.
- 9 J. Gao, Y. Xia, J. Zhao, P. Niu, Y. Fang, J. Shen and R. Xu, *IEEE Sens. J.*, 2022, **22**, 18391–18399.
- 10 A. Paghi, M. Corsi, S. Corso, S. Mariani and G. Barillaro, *Nanoscale Horizons*, 2022, **7**, 425–436.
- 11 T. Cui, L. Yang, X. Han, J. Xu, Y. Yang and T. Ren, *Materials (Basel)*, 2021, **14**, 6475.
- 12 T. Yin, Y. Cheng, Y. Hou, L. Sun, Y. Ma, J. Su, Z. Zhang, N. Liu, L. Li and Y. Gao, *Small*, 2022, 2204806.